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PII:	S0169-4332(15)00097-5
Reference:	APSUSC 29510
To appear in:	APSUSC
Received date: Revised date:	4-10-2014 24-12-2014
Accepted date:	10-1-2015

Please cite this article as: T.W. Reenaas, Y.S. Lee, F.R. Chowdhury, M. Gupta, Y.Y. Tsui, T.Y. Tou, S.L. Yap, S.Y. Kok, S.S. Yap, Femtosecond and nanosecond pulsed laser deposition of silicon and germanium, *Applied Surface Science* (2015), http://dx.doi.org/10.1016/j.apsusc.2015.01.073

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Femtosecond and nanosecond pulsed laser deposition of silicon and germanium

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Submission of a paper to Applied Surface Science

Femtosecond and nanosecond pulsed laser deposition of Si and Ge

Highlights

- Ge and Si were deposited by fs and ns laser at room temperature and at vacuum.
- Ion of 10^4 ms⁻¹ and 30-200 eV was obtained for ns ablation for Ge and Si.
- Highly energetic ions of 10^5 ms^{-1} with 2-7 KeV were produced in fs laser ablation.
- Nanocrystalline Si and Ge were deposited by using fs laser.
- Nanoparticles < 10 nm haven been obtained by fs laser.

Abstract

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